PTO/SB/21 (03-03) Approved for use through 04/30/2003, OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number Application Number 10/624,628 TRANSMITTAL Filing Date July 21, 2003 **FORM** First Named Inventor Luan C. Tran Art Unit 2812 (to be used for all correspondence after initial filing) **Examiner Name** Jennifer Kennedy Attorney Docket Number MI22-2356 Total Number of Pages in This Submission **ENCLOSURES** (Check all that apply) After Allowance Communication Fee Transmittal Form Drawing(s) to a Technology Center (TC) Appeal Communication to Board Licensing-related Papers Fee Attached of Appeals and Interferences Appeal Communication to TC Amendment/Reply (Appeal Notice, Brief, Reply Brief) Petition to Convert to a Proprietary Information After Final Provisional Application Power of Attorney, Revocation Status Letter Affidavits/declaration(s) Change of Correspondence Address Other Enclosure(s) (please Terminal Disclaimer **Extension of Time Request** Identify below): return receipt postcard; Request for Refund **Express Abandonment Request** CD, Number of CD(s) Information Disclosure Statement Remarks Certified Copy of Priority Document(s) Response to Missing Parts/ Incomplete Application Response to Missing Parts under 37 CFR 1.52 or 1.53 SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT Firm Jennifer J. Taylor, Ph.D.; Reg. No. 48,711; Wells St. John P.S. or Individual

Date Moranger/11, De	03
CER	FICATE OF TRANSMISSION/MAILING
I hereby certify that this correspondence is being facsim first class mail in an envelope addressed to: Commissio	transmitted to the USPTO or deposited with the United <u>States Postal Service with sufficient</u> postage as r for Patents, Washington, DC 20231 on this date:
Typed or printed	
Signature	Date

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 12 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, Washington, DC 20231.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.

## THE UNITED STATES PATENT AND TRADEMARK OFFICE

Apsimation Serial No
Filing Date July 21, 2003
Inventor Luan C. Tran
Assignee Micron Technology, Inc.
Group Art Unit
<b>priority</b> Examiner Kennedy, Jennifer J.
Attorney's Docket No MI22-2356
Title: Methods of Forming Semiconductor Constructions

itle: Methods of Forming Semiconductor Constructions

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (Official Gazette Notice: 05 August 2003). No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing date of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: 16 run/a 11, 2003

Jennifer J. Taylor,

Reg. No. 48,711

			U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO MI22-2356		SERIAL NO. 10/624.628				
			NT	APPLICANT Luan C. Tran							
NOV				FILING DATE July 21, 2003	GRO 2812	GROUP					
U.S. PATENT DOCUMENT					July 21, 2002						
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate				
	AA	6,144,079 A	11-2000	Shirahata et al.							
	AB	6,033,952	03-2000	Yasumura, et al.							
	AC	6,124,168	09-2000	Ong	-						
	AD	5,688,705	11-1997	Bergemont							
	AE	5,866,448	02-1999	Pradeep et al.							
	AF	5,858,847	01-1999	Zhou et al.	<u> </u>		÷				
	AG	6,380,598	04-2002	Chan							
	AH	6,060,364	05-2000	Maszara et al.							
	AI	6,194,276 B1	02-2001	Chan et al.							
	AJ	6,359,319 B1	03-2002	Noda							
	AK	5.164,806	11-1992	Nagatomo et al.							
	AL 4,937,756 06-1990			Hsu et al.							
	Document Date			FOREIGN PATENT DOCUMENT Country	Country			Translation			
		Number				Class	Subclass	Yes	No		
·	AM	EP 0718881	06/96	EPO, Chan							
	AN	****						·			
	AO										
	AP	го	HER REFEREN	CES (including Author, Title, Date	, Pertinent Pages, Etc.)						
	AR	Watanabe, H. et al Embedded Applicat	., Novel 0.44µm ion, IEEE 1998,	<sup>2</sup> Ti-Salicide STI Cell Technology pp. 36.2.1 - 36.2.4.	y for High-Density NOI	R Flash Memoi	ies and H	ligh Performan	ice		
					_						
	AS	Wolf, S., *Silicon F	Wolf, S., *Silicon Processing for the VLSI Era*, Vol. 2, pp. 632-635.								
	АТ		MITSUBISHI ELECTRIC WEBSITE: Reprinted from website <a href="http://www.mitsubishielectric.com/r and d/tech showcase/ts8.php">http://www.mitsubishielectric.com/r and d/tech showcase/ts8.php</a> on 3/29/2001: *8. Production Line Application of a Fine Hole Pattern-Formation Technology for Semiconductors*, on 3/29/2001, 4 pgs								
EXAMINER				DATE CONSIDER	ED						
		reference considered, whether with next communication to		is in conformance with MPEP 609	9; Draw line through ci	tation if not in	conforma	nce and not co	ensidered.		

PATENT AND			DEPARTMENT OF COMMERCE NT AND TRADEMARK OFFICE	ATTY. DOCKET N MI22-2356		SERIAL NO. 10/624.628				
PATENT AND TRA  NOV 1 3 2008 ISP OF ART CITED BY APPLICANT  (Use several sheets if necessary)			NT	APPLICANT Luan C. Tran						
A STATE OF THE STA				FILING DATE July 21, 2003	OATE GROUP					
A Promise of the Control of the Cont				U.S. PATENT DOCUMENTS	July 21, 2003		2012			
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate			
	AA	5,930,614	07-1999	Eimori et al.						
	AB	5,635,744	06-1997	Hidaka et al.						
	AC	6,204,536	03-2001	Maeda et al.						
	AD	6,515,899 B1	02-2003	Tu et al.						
	AE	4,570,331	02-1986	Eaton, Jr. et al.						
	AF	6,429,079 B1	08-2002	Maeda et al.						
	AG	6,607,979 B1	08-2003	Kamiyama						
	АН	4,686,000	08-1987	Heath						
	AI	5,814,875	09-1998	Kumazaki						
	AJ	5,654,573	08-1997	Oashi et al.						
	AK	6,479,330 B2	11-2002	1002 Iwamatsu et al.						
	AL	6,586,803	07-2003	Hidaka et al.						
			,	FOREIGN PATENT DOCUMENT	rs					
		Document Number	Date	Country			Subclass		lation	
	AM							Yes	No	
	AN									
	AO									
	AP									
		Oi	THER REFEREN	CES (including Author, Title, Date,	, Pertinent Pages, Etc.)					
	AR	CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semiconductor/issues /1999/sep99/ docs/feature1.asp on 3/29/2001: "Resists Join the Sub-λ Revolution", 9 pgs.								
	AS	CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from <a href="http://www.semiconductor.net/">http://www.semiconductor.net/</a> semiconductor/issues/1999/aug99/docs/lithography.asp on 3/29/2001: "Paths to Smaller Features", 1 pg.								
	АТ	Wolf, S., "Silicon F	Processing for th	e VLSI Era, Vol. 1: Process Te	echnology," Lattice Pre	ss 1986, p	p. 434-437.			
EXAMINER				DATE CONSIDER	ED					
		reference considered, whether with next communication to		is in conformance with MPEP 609	9; Draw line through c	itation if not	in conformar	nce and not co	onsidered.	

Form PTO-1449 NOV 1 3 2003	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2356	SERIAL NO. 10/624,628		
LIST OF SAT CITED BY	APPLICANT Luan C. Tran				
& TRADEM		FILING DATE July 21, 2003	GROUP 2812		

July 21, 2003 2812										
U.S. PATENT DOCUMENTS										
*Examiner Initial		Document Number	Date		Name		Class	Subclass	Filing Date If Appropriate	
	AA	6,552,401 B1	04-2003	Dennison						
	AB	6,627,524 B2	09-2003	Scott	<del>-</del>				_	
	AC	US2002/0182829A1	12-2002	Chen	<u>.</u>		·			
	AD	US2002/0164846A1	11-2002	Lin et al.					Apr. 19, 2002	
	AE	US2003/0071310A1	04-2003	Salling et	al.	,			Oct. 11, 2001	
	AF									
	AG									
	АН									
	AI									i
	ΑJ									
	AK									
	AL									
				FOREIGN	PATENT DOCUMENTS				•	
		Document Date Number			Country		Class	Subclass		lation
			<del> </del>						Yes	No
	AM AN									
	AO									
	AP									
		o	THER REFEREN	ICES (includ	ing Author, Title, Date, Pe	ertinent Pages, Etc.)			_	
	AR	"Session 18: Integrated Circuits and Manufacturing - DRAM and Embedded DRAM Technology," 2001 IEDM Technical Program, 2001 IEEE International Electron Devices Meeting, Dec. 4, 2001, reprinted 11/15/01 from <a href="http://www.his.com/~iedm/techprogram/sessions/s18.html">http://www.his.com/~iedm/techprogram/sessions/s18.html</a> , pp. 1-2.								
	AS									
						<del> </del>		·		
	AT							_		
				_					_	
EXAMINER DATE CONSIDERED										

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.